

FIG. 1A PRIOR ART

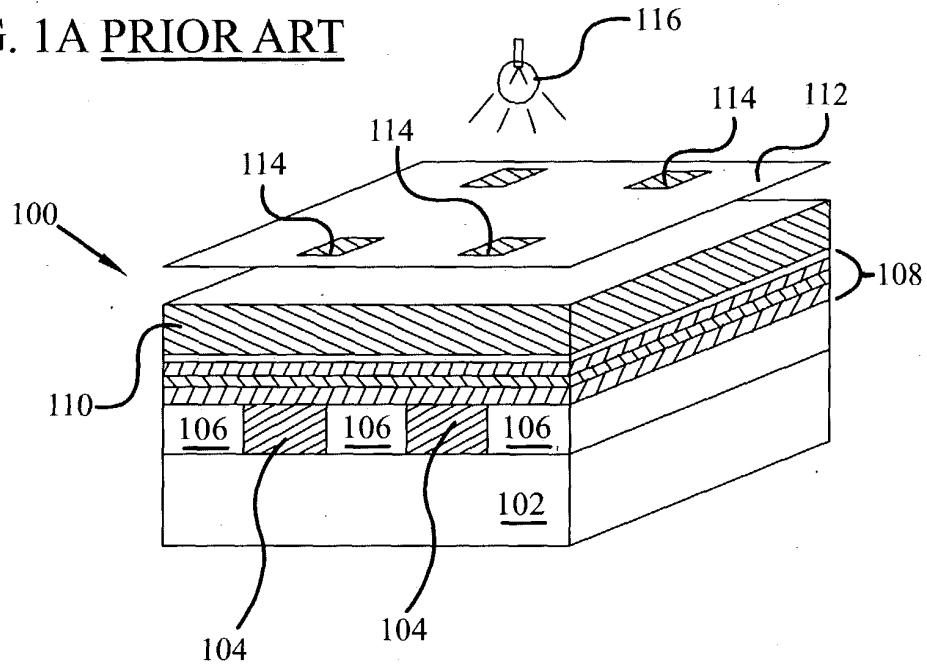
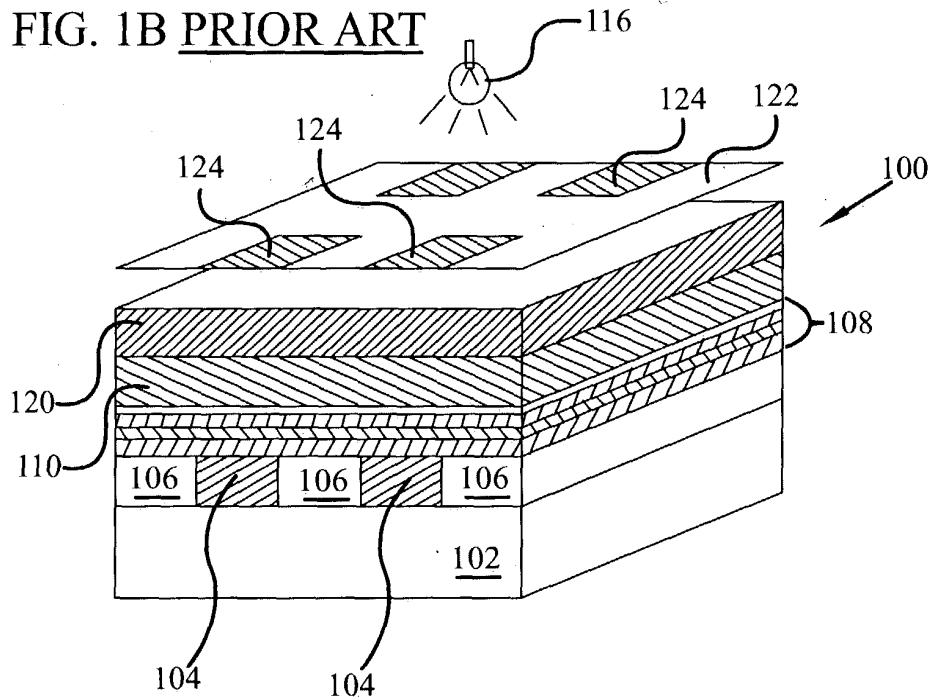


FIG. 1B PRIOR ART



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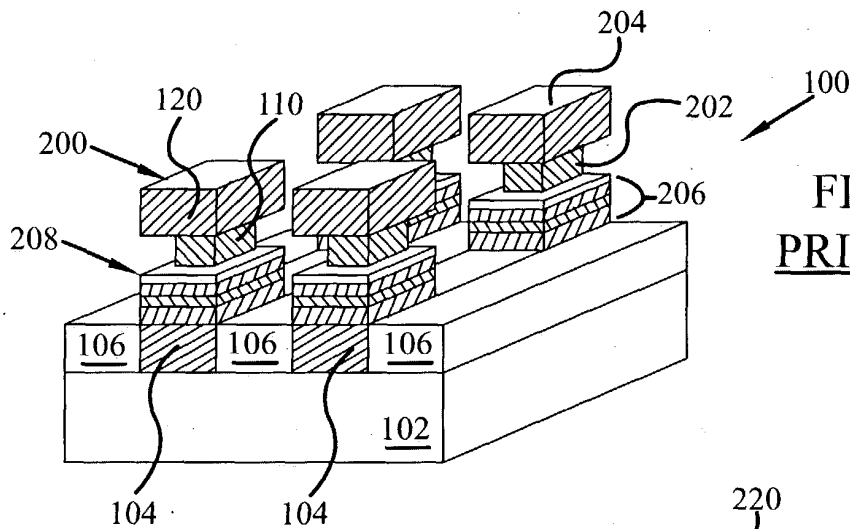


FIG. 2A
PRIOR ART

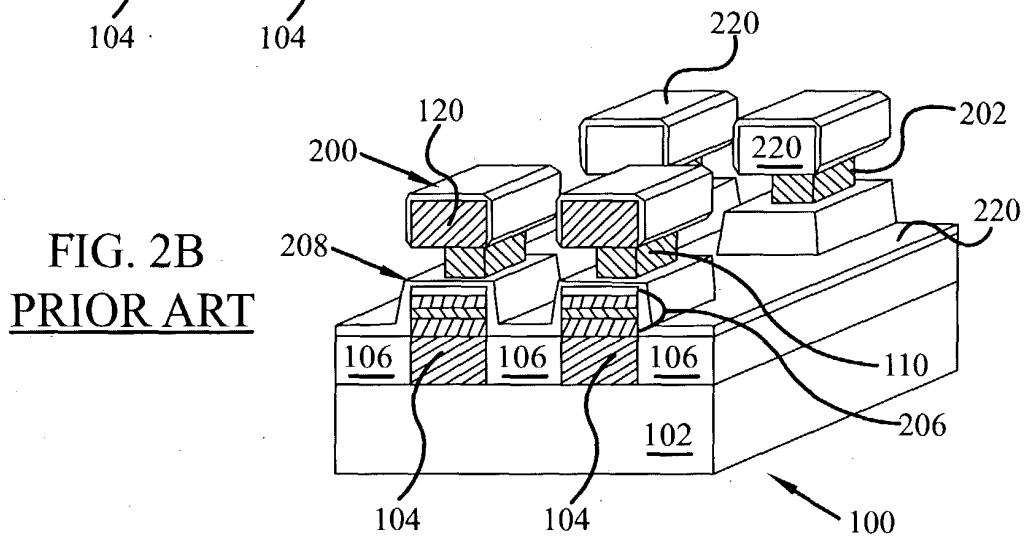


FIG. 2B
PRIOR ART

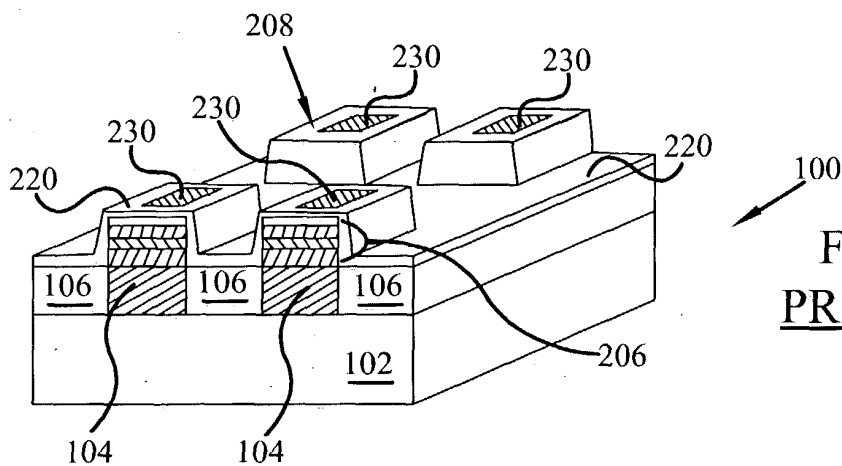
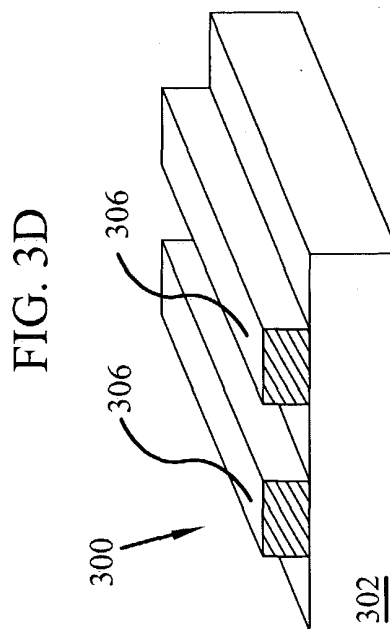
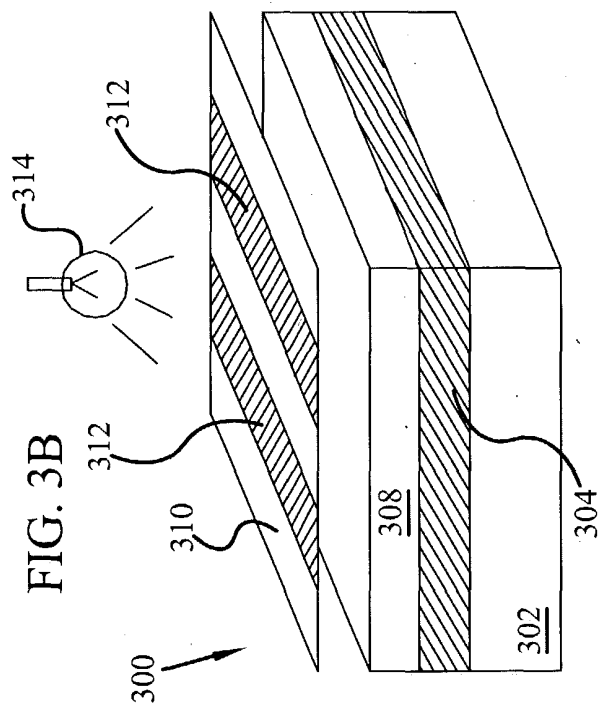
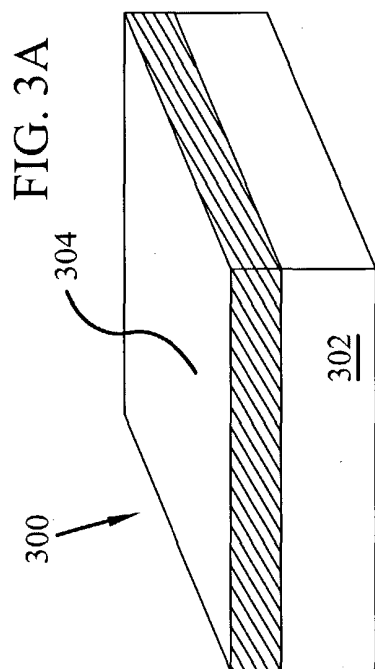
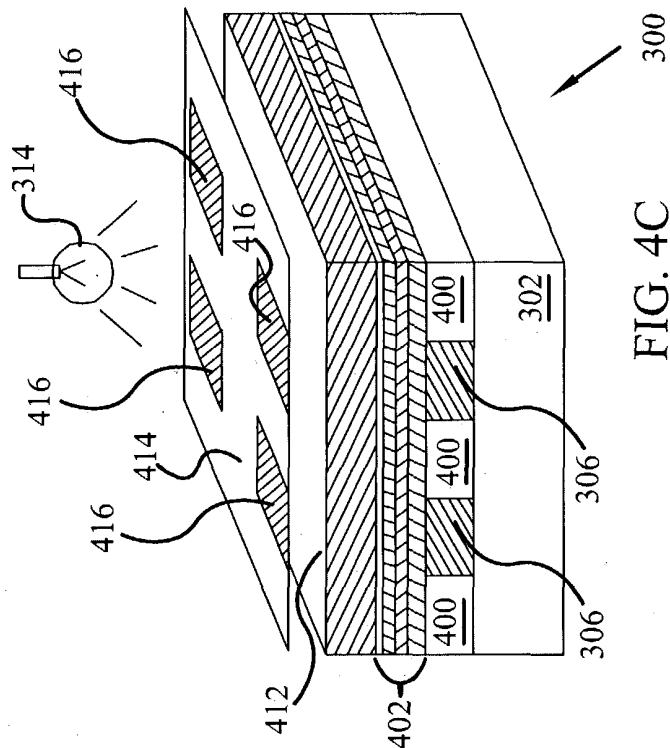
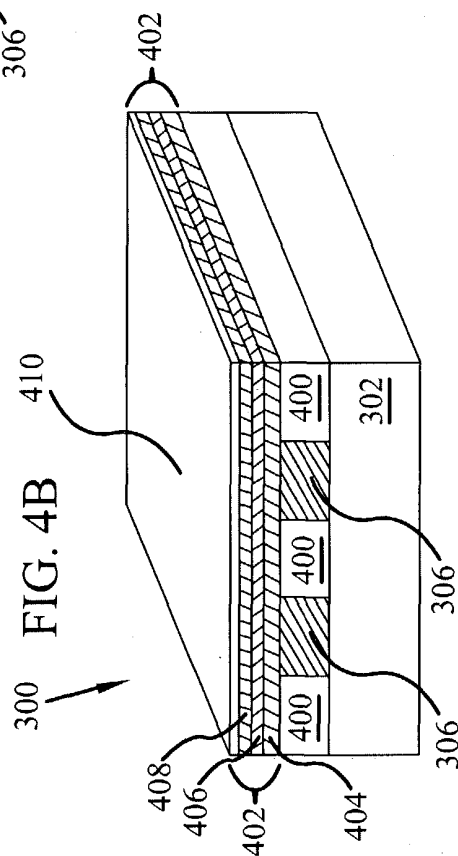
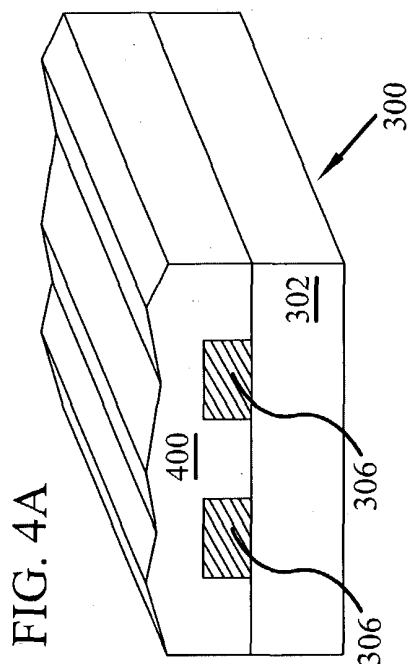
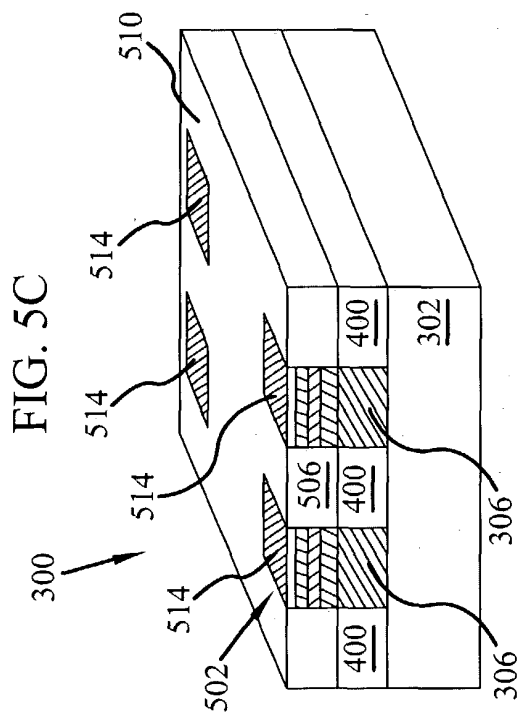
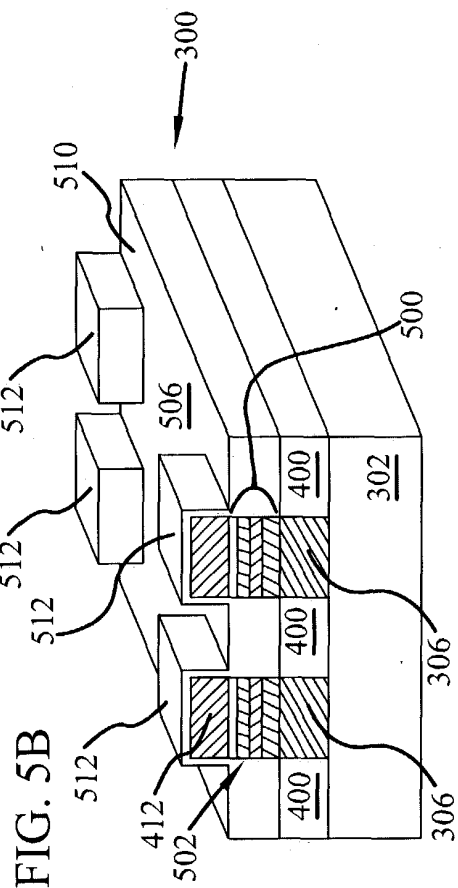
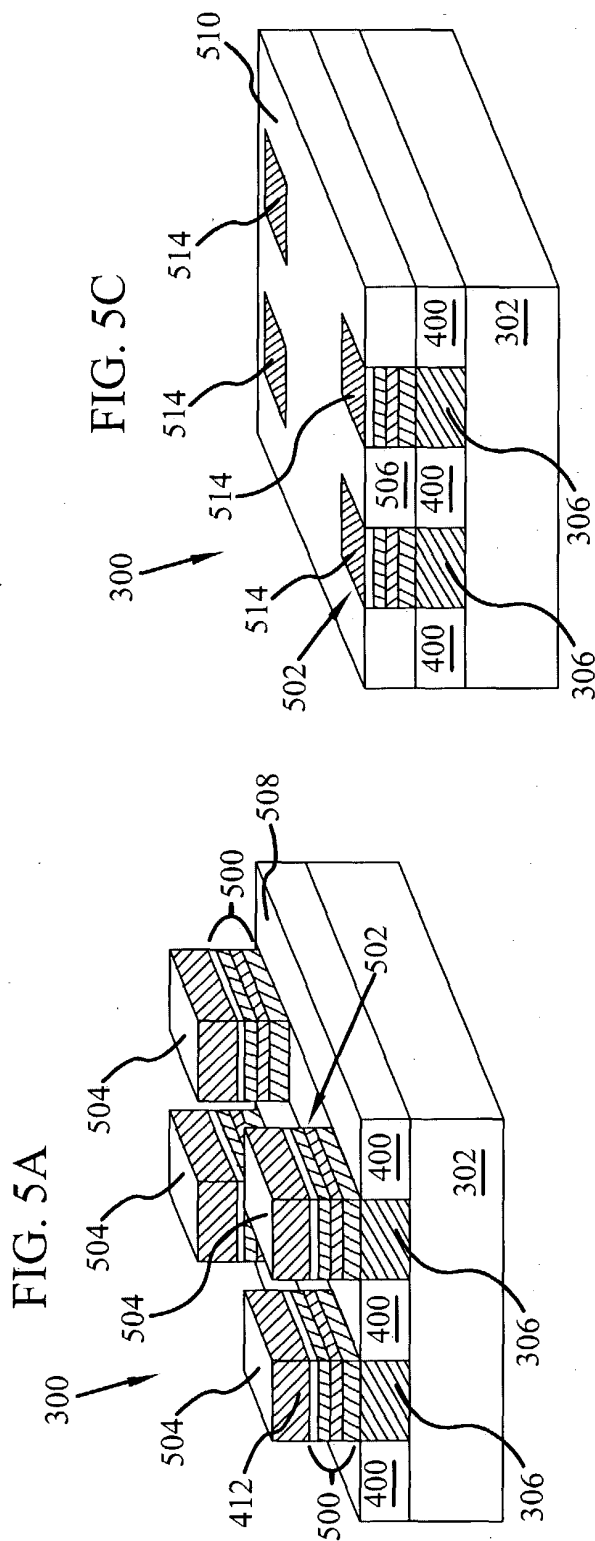


FIG. 2C
PRIOR ART







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FIG. 6A

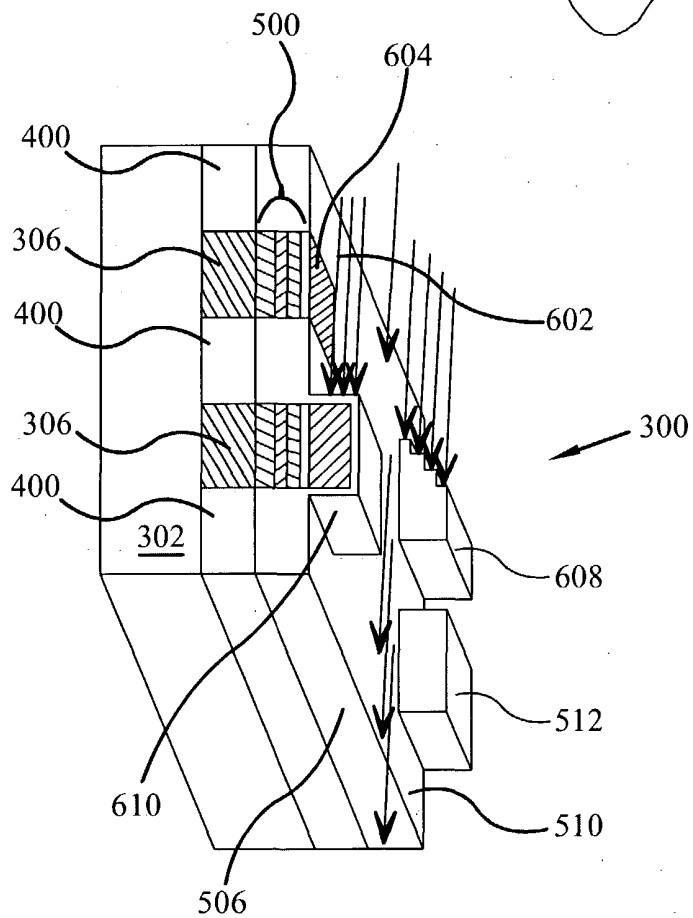
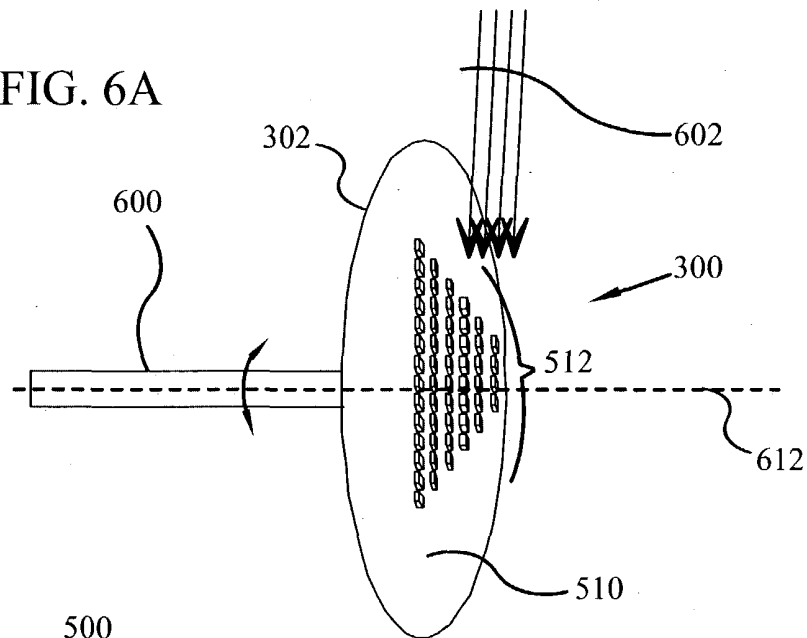


FIG. 6B

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